

PATENT

IBM/293  
Confirmation No. 6082

**CERTIFICATE OF ELECTRONIC TRANSMISSION**

I hereby certify that this correspondence for Application No. 10/814,482 is being electronically transmitted to Technology Center 2818, via EFS-WEB, on May 4, 2006

/William R. Allen/  
William R. Allen

May 4, 2006  
Date

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Toshiharu Furukawa, et al.                      Art Unit: 2818  
Serial No.: 10/814,482    Examiner: David J. Goodwin  
Filed: March 31, 2004    Atty. Docket No.: ROC9200300399US1  
For: METHOD FOR FABRICATING STRAINED SILICON-ON-INSULATOR  
STRUCTURES AND STRAINED SILICON-ON-INSULATOR STRUCTURES  
FORMED THEREBY

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**RESPONSE TO RESTRICTION REQUIREMENT**

Mail Stop AMENDMENT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action of April 27, 2006, please amend the above-identified application as follows:

**Amendments to the claims** are reflected in the listing of claims that begins on page 2 of this paper.

**Remarks** begin on page 5 of this paper.